

Fig 22
 Ideal CMOS structure for high performance
 [120]

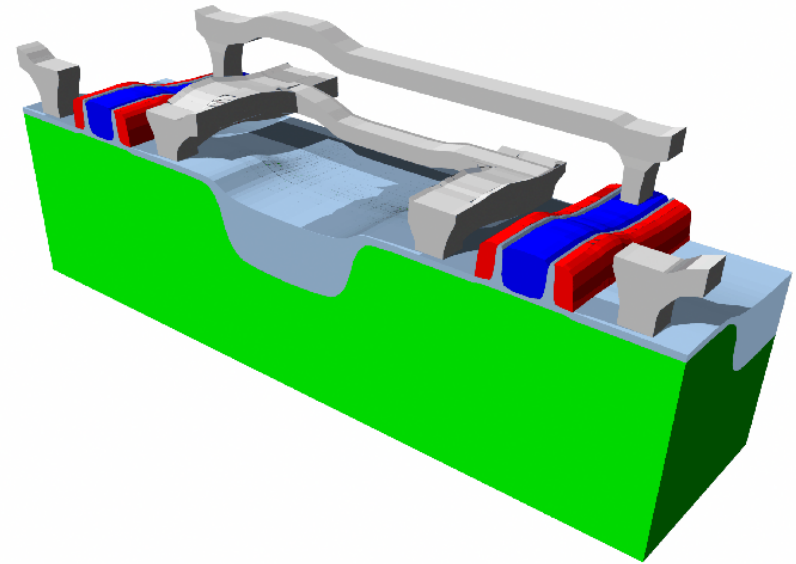


Figure 7.24: Typical CMOS inverter structure with two transistors.

Repetition:

- Nanostrukturierung: Warum? Wo? Wie? -- Beispiele
- Bottom-Up vs. Top Down
- Bottom-Up Nanostrukturieren:
 - Spielen mit Physikalischen / Chemischen WW
- Oberflaechen und Vakuum Warum? Wieviel?

Nanostructures and Nanostructuring

20. / 27. Sept 2011

- Bildungs- und Wachstumsmechanismen
- Oberflächendiffusion
- Wachstumsmoden (ballistisch, dendritisch)
- amorph, poly, einkristallin
- Epitaxie

Nanostructures: Important concepts

Dimensionality	'dot' vs 'wire' vs sheet
Ratio Bulk I vs Bulk II	'matrix & filler', ceramic
Controlling by size effects	'optic', 'electronic' etc.
Controlling by anisotropy	'polymer – polarizer'
Controlling contact area	'lotus effect'
Controlling by proximity @ Interface	'field effect transistor'
Sub-wavelength optics (diffraction)	'~ photons, $\varepsilon \sim 1$

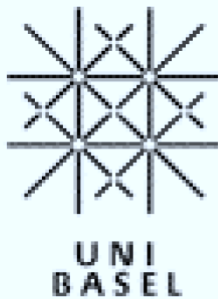
...

Important: Nanostructuring: Mostly 2D or pseudo 3D
3D: wishful thinking but enormous potential
('brain' vs 'processor')

Crucial: Control 'Surface / Interface active components'
→ need very clean materials ($\sim d^3$) / surfaces (d^2)

Surface Physics 2010

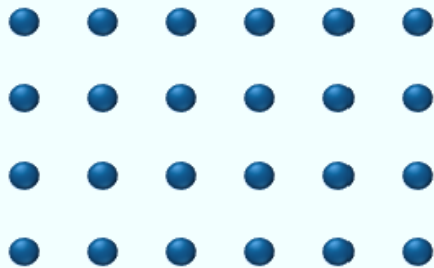
Surface Diffusion



Lecturer: Dr. Enrico Gnecco
NCCR Nanoscale Science

Random-Walk Motion

- Thermal motion of an adatom on an ideal crystal surface:



- Thermal excitation \rightarrow the adatom can hop from one adsorption site to the next

- Mean square displacement at time t :

$$\langle \Delta r^2 \rangle = \nu a^2 t$$

a = jump distance; ν = hopping frequency

(Note that νt = number of hops!)

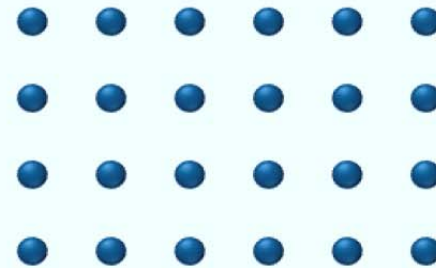
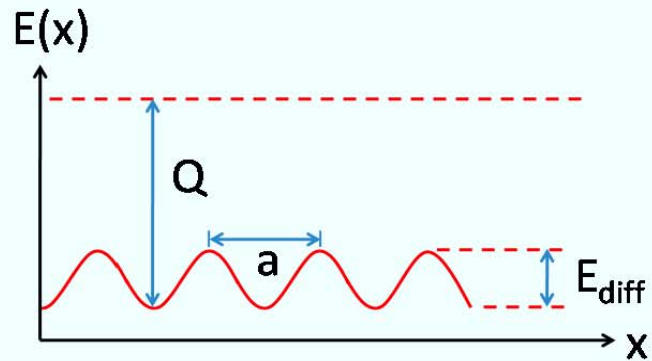
- **Diffusion coefficient:**

$$D = \frac{\langle \Delta r^2 \rangle}{z t} = \frac{\nu a^2}{z}$$

z = number of first neighbors = $\begin{cases} 2 \text{ in 1D diffusion} \\ 4 \text{ on a square lattice} \\ 6 \text{ on a hexagonal lattice} \end{cases}$

Random-Walk Motion

- Hopping → surmounting a potential barrier



- Arrhenius law:

$$\mathbf{v = v_0 \exp\left(-\frac{E_{diff}}{k_B T}\right)}$$

v_0 = oscillation frequency of the atom in the well;
 E_{diff} = barrier height

Typically $E_{diff} \sim 5\text{-}20\%$ of Q (heat of desorption)

- For chemisorbed species: $E_{diff} \gg k_B T$
- If $E_{diff} < k_B T$: 2D gas (only a few physisorbed species)

Fick's Laws

- **Fick's First Law** (for 1D diffusion):

$$J = -D \frac{\partial c}{\partial x}$$

diffusion flux concentration gradient

(flux → region of lower concentration)

- **Fick's Second Law** (for 1D diffusion):

$$\frac{\partial c}{\partial t} = D \frac{\partial^2 c}{\partial x^2}$$

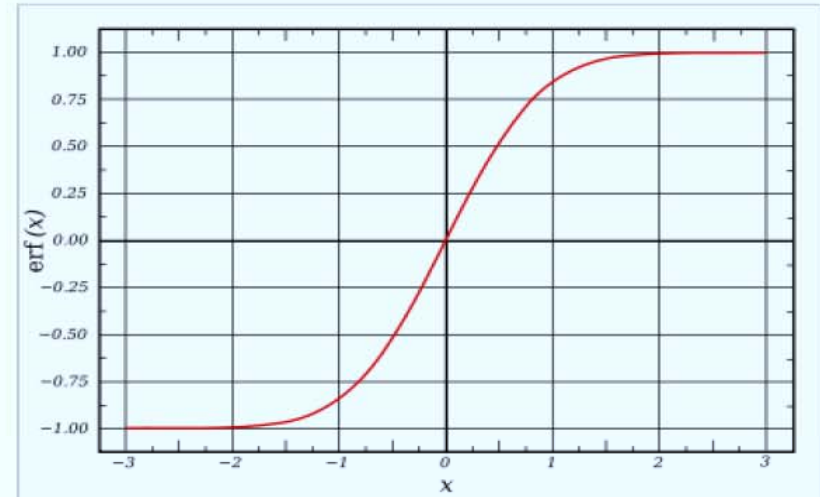
← from equation of continuity

- Analytical solutions can be found for specific initial and boundary conditions!

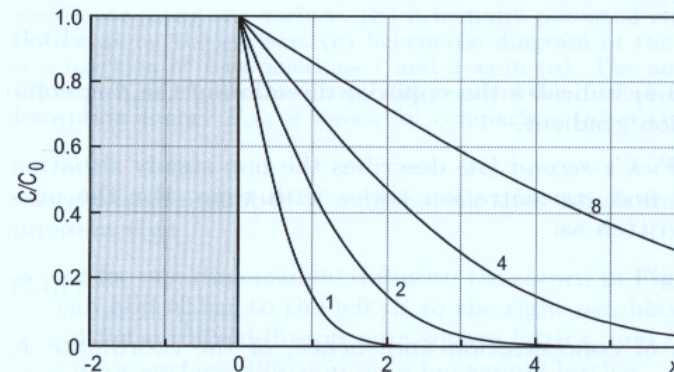
Analytical Solutions of Fick's Laws

- We introduce the **error function**

$$\text{erf}(x) = \frac{2}{\sqrt{\pi}} \int_0^x \exp(-t^2) dt$$



- Source of constant concentration:



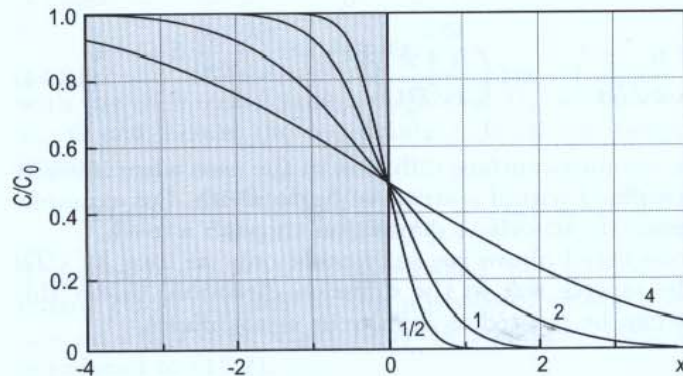
$$c(x,t) = c_0 \left[1 - \text{erf} \left(\frac{x}{2\sqrt{Dt}} \right) \right]$$

$2\sqrt{Dt}$: **diffusion length**

- Example: Submonolayer film with 3D islands supplying mobile adatoms

Analytical Solutions of Fick's Laws

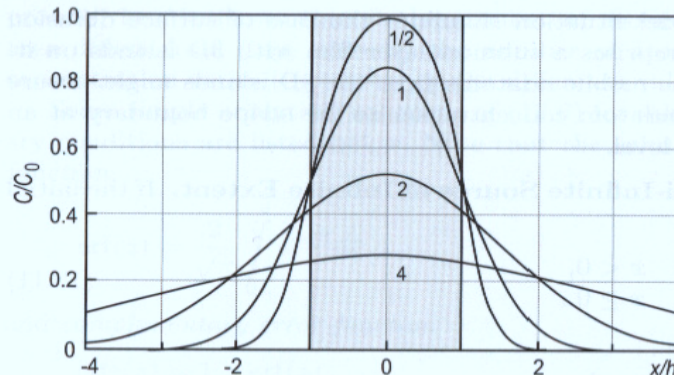
- Source of infinite extent:



$$c(x,t) = \frac{c_0}{2} \left[1 - \operatorname{erf} \left(\frac{x}{2\sqrt{Dt}} \right) \right]$$

- Example: Submonolayer film

- Source of limited extent:



$$c(x,t) = \frac{c_0}{2} \left[\operatorname{erf} \left(\frac{h-x}{2\sqrt{Dt}} \right) + \operatorname{erf} \left(\frac{h+x}{2\sqrt{Dt}} \right) \right]$$

- Example: Submonolayer film confined in a stripe of finite width

Diffusion Mechanisms

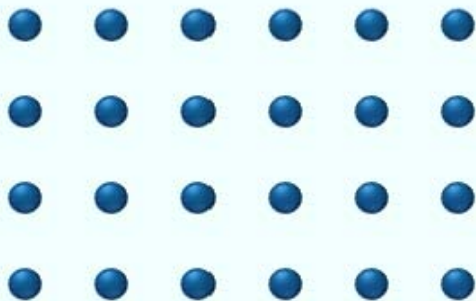
- Depending on the coverage Θ :
 - Tracer diffusion (low Θ)
 - Chemical diffusion (intermediate to high Θ)



Tracer Diffusion

- **Tracer Diffusion:**

- Low coverage (<0.01 ML)
- Individual adparticles



- Fick's first law is valid:

$$D = \frac{\langle \Delta r^2 \rangle}{z t}$$

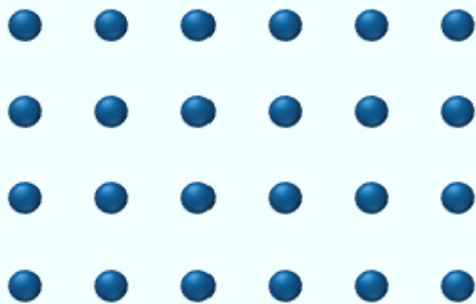
- For an ensemble of many particles:

$$D = \frac{1}{z N t} \sum_i \langle \Delta r_i^2 \rangle$$

(no relation to radioactive tracers!)

Chemical Diffusion

- **Chemical Diffusion:**
 - Higher coverage
 - Attraction or repulsion between adatoms



- Fick's first law can be generalized:

$$J = -D_c(\Theta) \frac{\partial \Theta}{\partial x}$$

chem. diff. coefficient

coverage

- Strong dependence on adsorbate coverage is expected, especially when ordered phases are formed (Naumovets-Vedula, 1986)

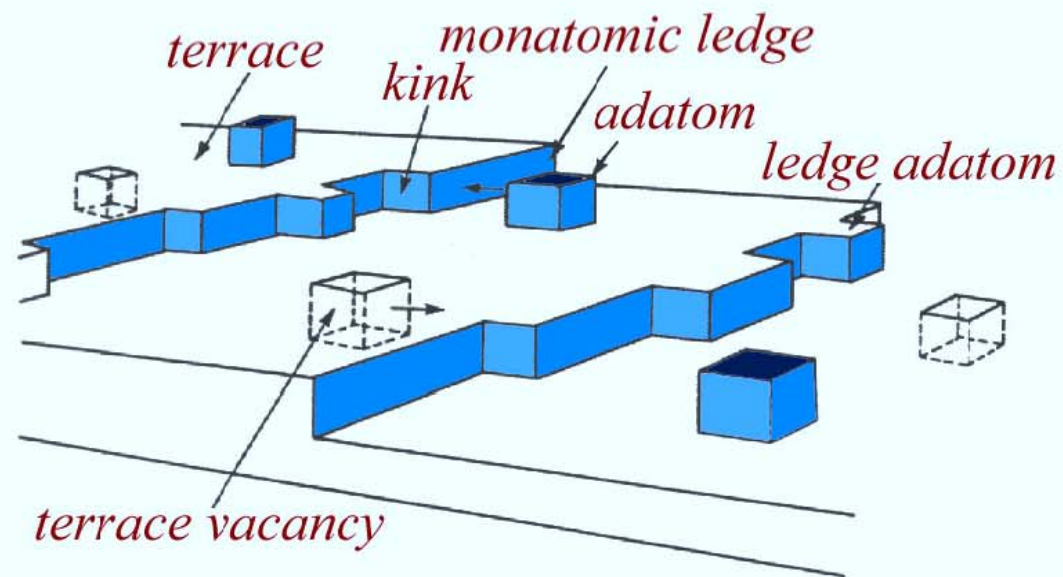
Diffusion Mechanisms

- Depending on the landscape:
 - Intrinsic diffusion (no sources and traps)
 - Mass transfer diffusion (generation and/or trapping)



Intrinsic Diffusion

- Adparticle motion is monitored within a single terrace → Spatial limit ~ 100 nm
- In practice: no strong distinction from tracer diffusion



Mass Transfer Diffusion

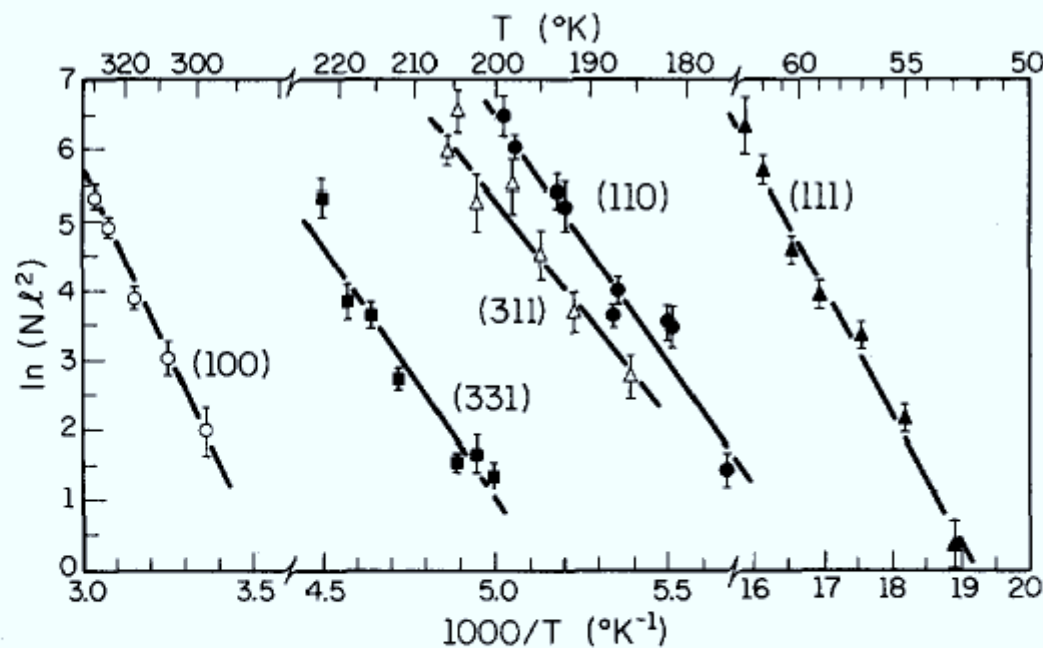
- Real surfaces contain defects (steps, kinks, adatoms or vacancy clusters, etc.)
- If average separation between defects < diffusion length → number of mobile particles (and diffusion) become strongly temperature dependent
- If adatoms and substrate are the same chemical species:

$$D = \frac{v_0 a^2}{z} \exp\left(-\frac{\Delta G + E_{diff}}{k_B T}\right) \quad \Delta G = \text{energy of adatom formation}$$

(→ two types of energy barriers!)

Anisotropy of Surface Diffusion

- **Orientalional Anisotropy:** the diffusion coefficient depends on the orientation of the surface
- Example: Rh surfaces at different T (Ayrault & Ehrlich, JCP 1974)

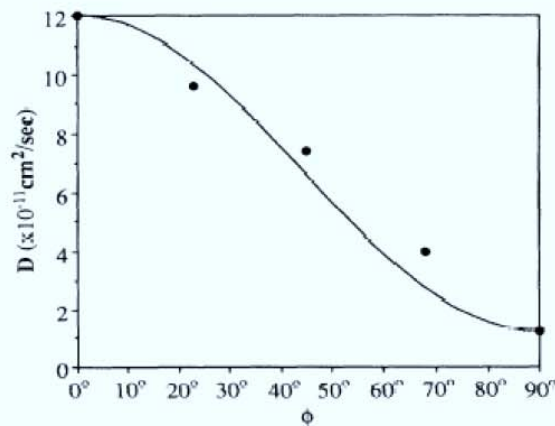


N: number of jumps in 3 min
 l : jump distance

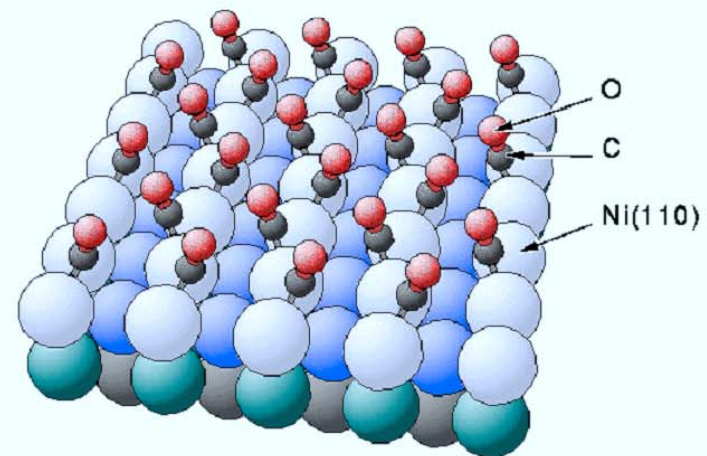
- At given T the differences in the diff. coeff. can be several orders of magnitude!

Anisotropy of Surface Diffusion

- **Directional Anisotropy:** the diffusion coefficient depends on the direction at the surface
- Rectangular lattice \rightarrow directional anisotropy (Xiao et al., PRL 1991)

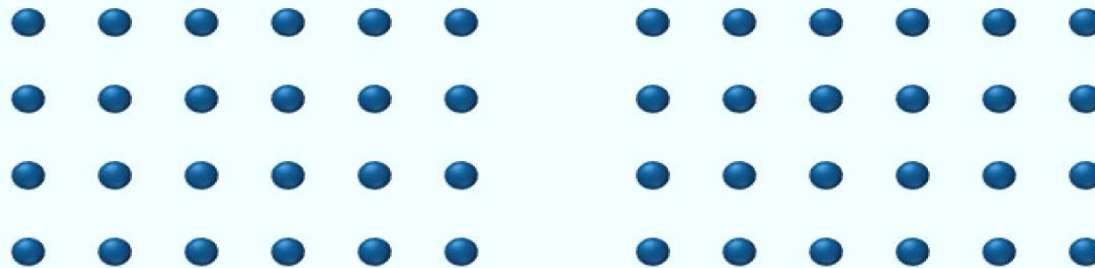


$$D(\varphi) = D_x \cos^2 \varphi + D_y \sin^2 \varphi$$

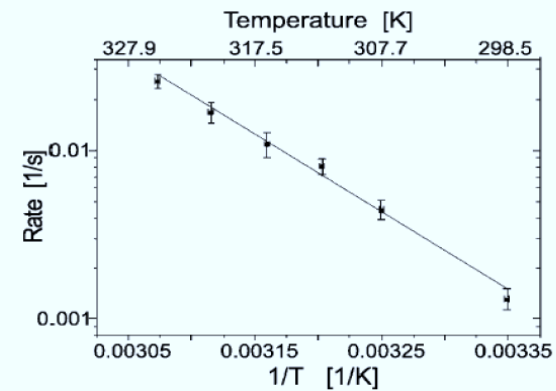
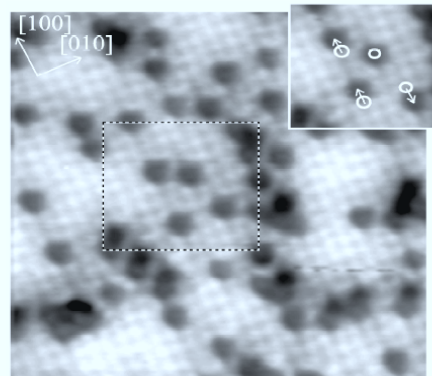


Atomistic Mechanisms

1) Hopping mechanism:



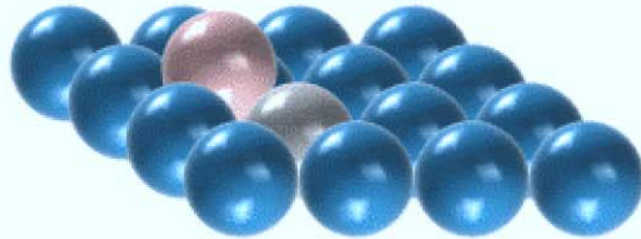
- Example: N adatoms on Fe(100) (Pedersen et al., PRL 2000)



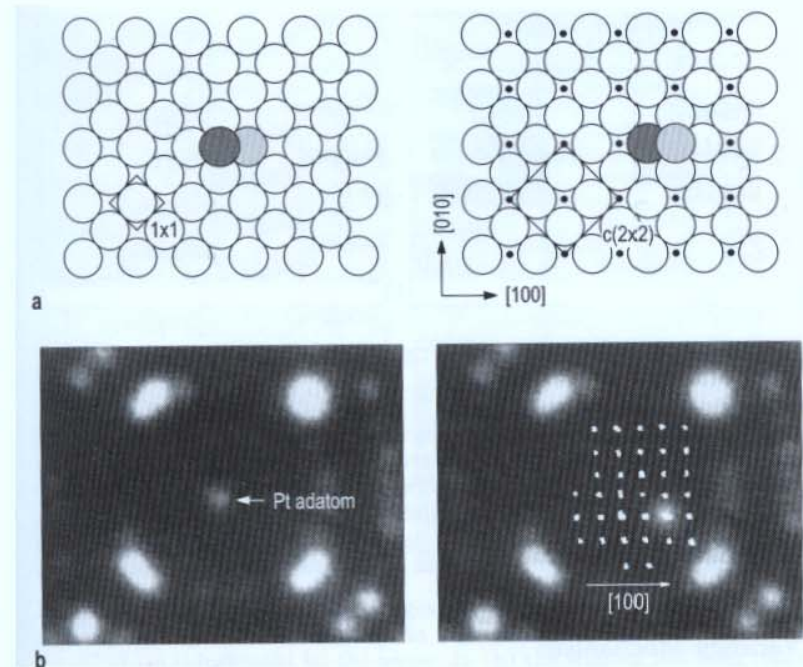
→ Arrhenius law with $\nu \sim 10^{12} \text{ s}^{-1}$, $E_{diff} = 0.92 \text{ eV}$

Atomistic Mechanisms

2) Atomic exchange mechanism:



- Example: Pt adatom on Pt(100) (Kellogg, SSR 1994)

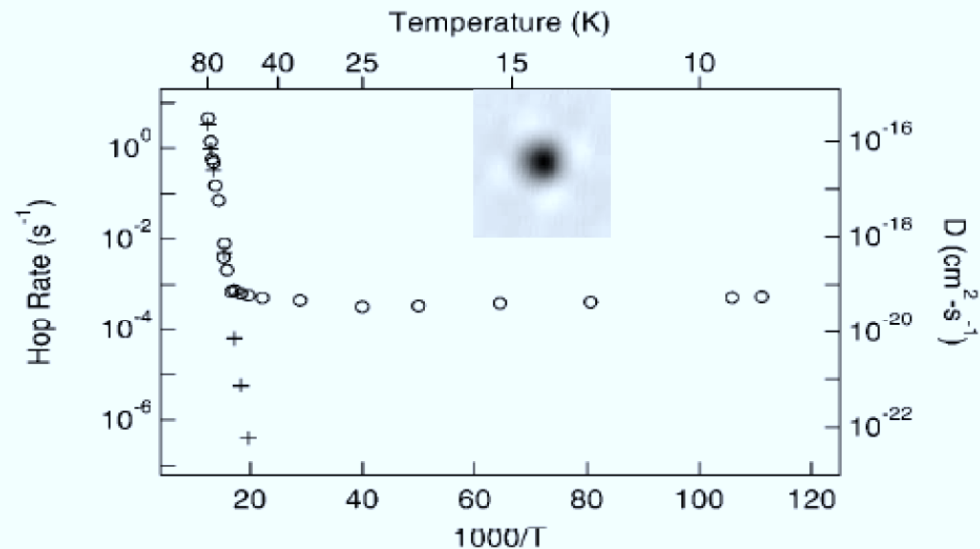


- Observed also on heterosystems [Pt on Ni(110), Ir on Pt(100), Re on Ir(100)]

Atomistic Mechanisms

3) Tunneling mechanism:

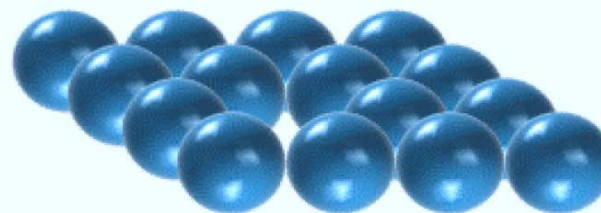
- Diffusing particle with small mass
- Low potential barrier against diffusion
- Example: Hydrogen on Cu(100) (Lauhon & Ho, PRL 2000)



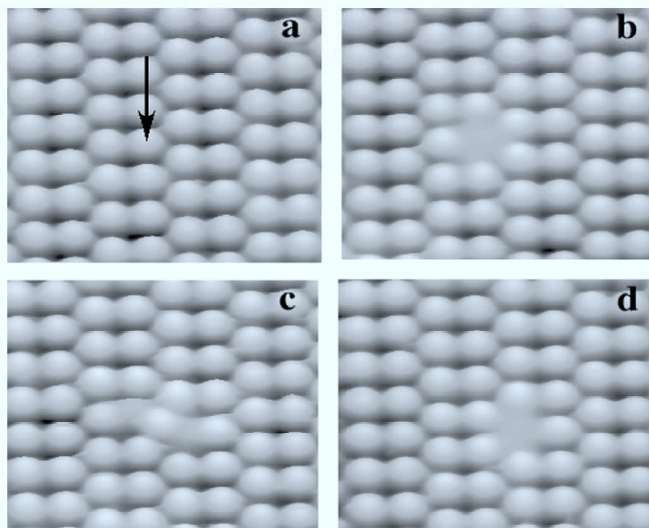
- Above 60 K: Arrhenius law with $\nu \sim 10^{13} \text{ s}^{-1}$, $E_{diff} = 0.20 \text{ eV}$
- Below 60 K: quantum tunnelling, T independent

Atomistic Mechanisms

4) Vacancy mechanism:



- Example: Ge(111)c(2x8) (Mayne et al., SS 2001)



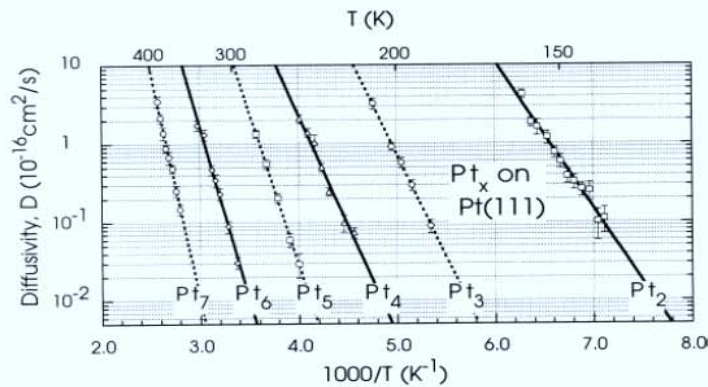
-Vacancy created with the STM tip

- T-activated hopping of neighboring atoms

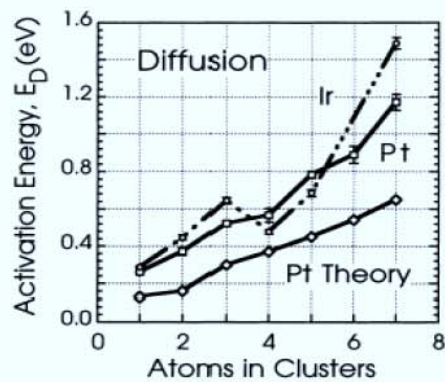
- Heterodiffusion by vacancy-exchange also reported

Cluster Diffusion

- The larger the cluster, the lower its mobility:

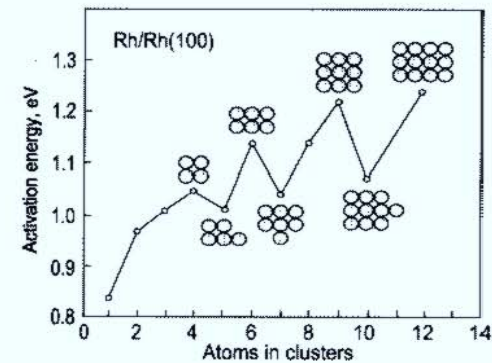


- Activation energy increases with cluster size:



(Kyuno & Ehrlich, SS 1999)

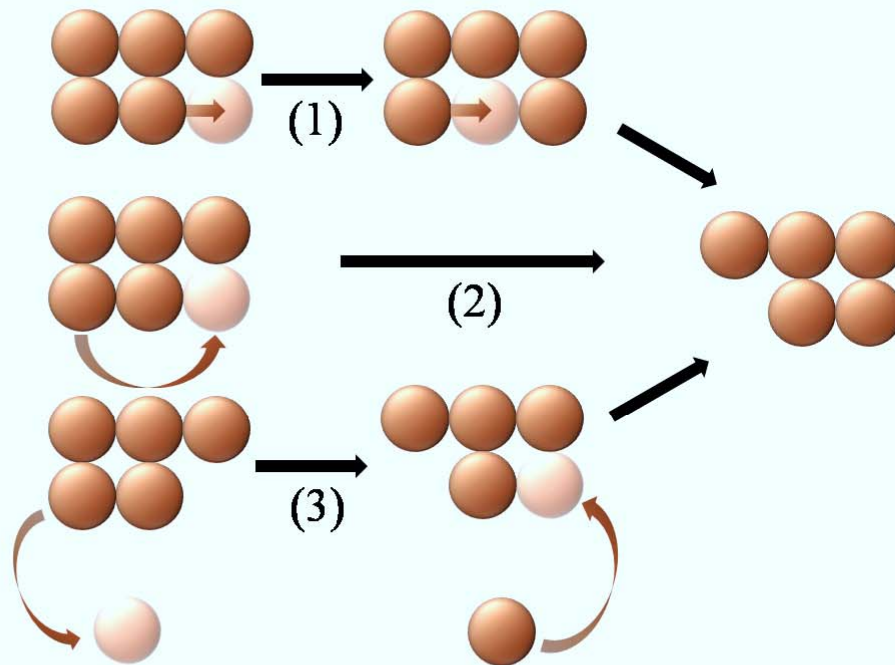
- Compact shapes are less mobile...



(Kellogg, PSS 1996)

Cluster Diffusion

Individual mechanisms:



(1) Sequential displacement

(2) Edge diffusion

(3) Evaporation-condensation

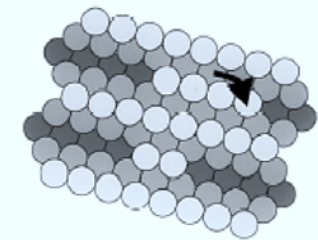
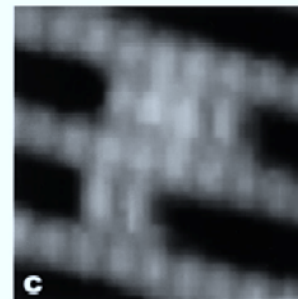
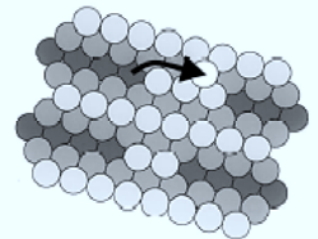
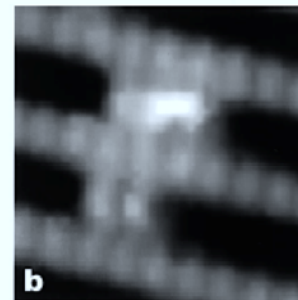
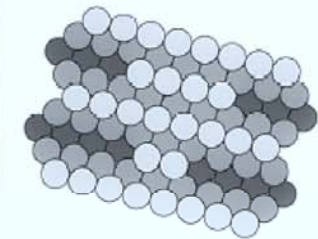
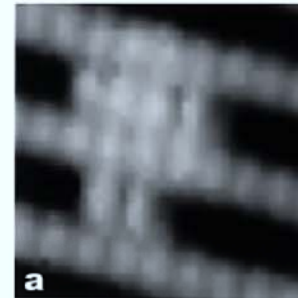
Cluster Diffusion

Individual mechanisms:

(4) “Leapfrog” mechanism:



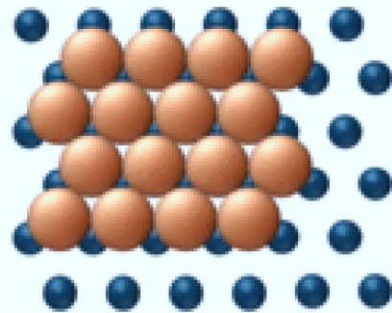
- Example: Pt(110)2x1 (Linderoth et al., PRL 1999)



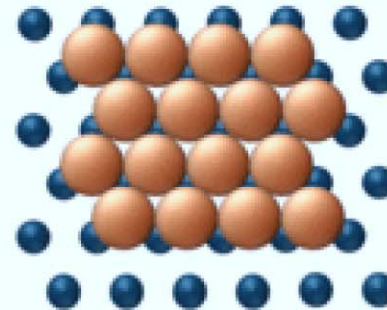
Cluster Diffusion

Concerted mechanisms:

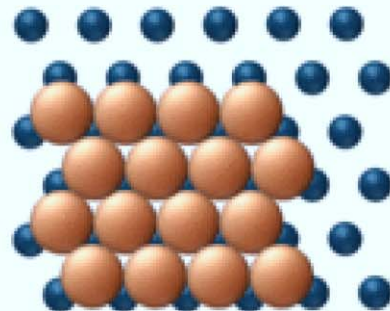
(1) Glide:



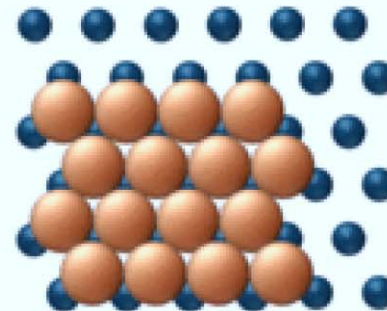
(2) Shear:



(3) Reptation:

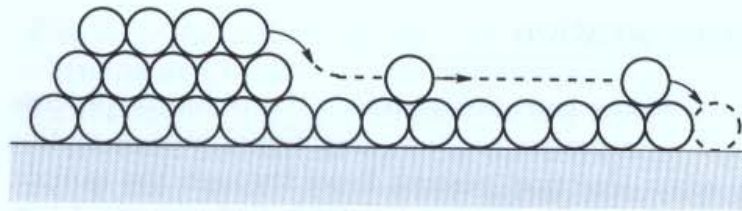


(4) Dislocation:



Phase Formation

- Coverage $\Theta \sim 0.1-1$ ML \rightarrow formation of surface phases
- First layer atoms are usually immobile \rightarrow “unrolling carpet” mechanism



Surface Electromigration

- Electric current through the sample \rightarrow Directional atomic motion on the surface
- Self-electromigration \rightarrow Changes in the step structure
- Hetero-electromigration \rightarrow Mass transfer towards cathode or anode

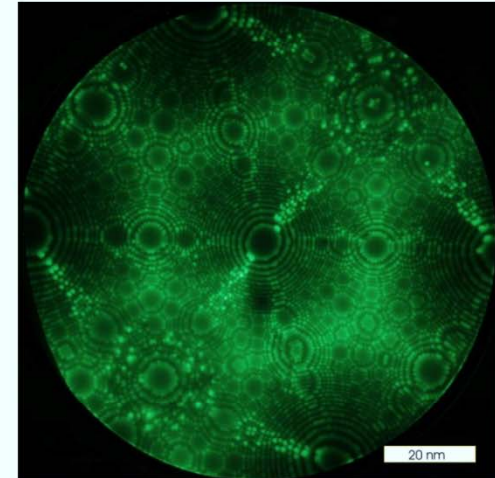
Experimental Techniques

1) Direct observation:

- Field ion microscopy (FIM)

→ “image-anneal-image” technique

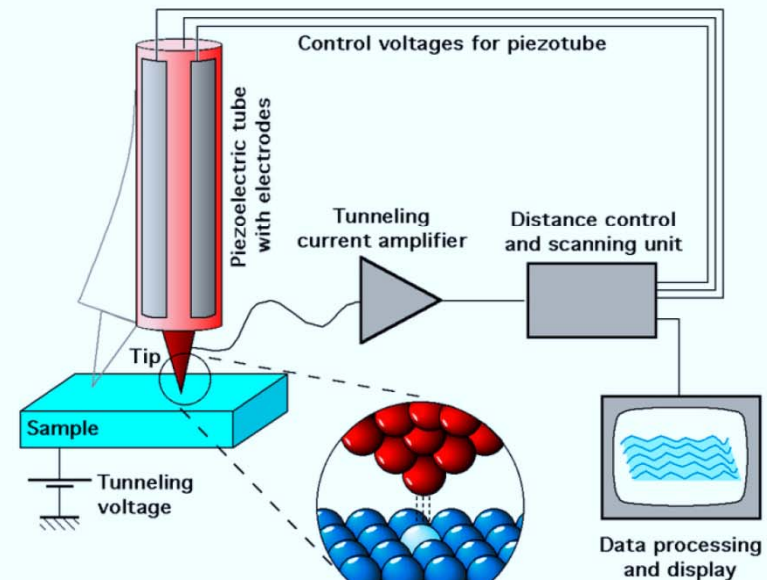
- Limited to refractory or noble metal surfaces



- Scanning tunneling microscopy (STM)

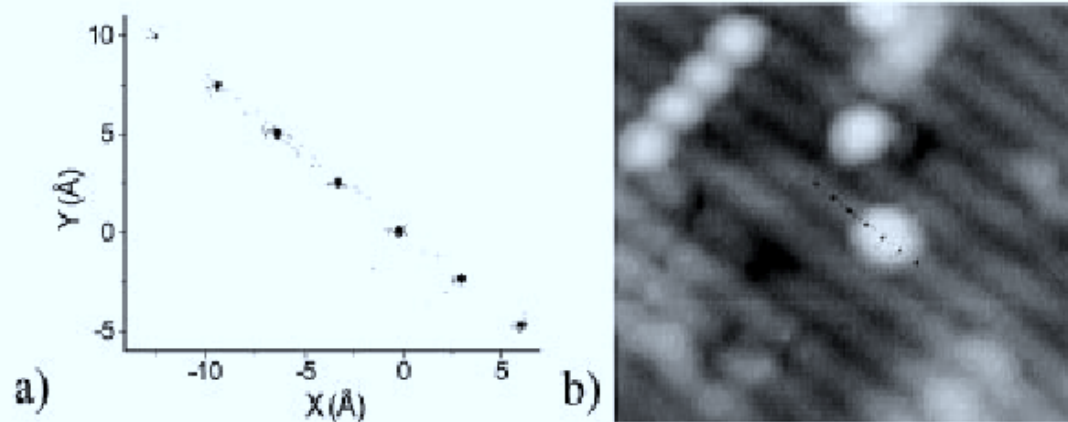
→ “image-while-hot” technique

- STM “movies” can be recorded (at 0.01-1 frames per second)



Experimental Techniques

- Scanning tunneling microscopy (STM) → “atom-tracking” technique
 - STM tip locked onto an adparticle by 2D lateral feedback
 - Example: Si on Si(100) (Swartzentruber, PRL 1996)

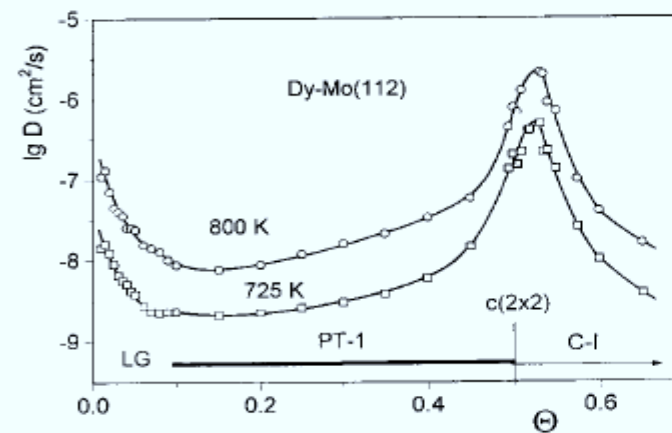
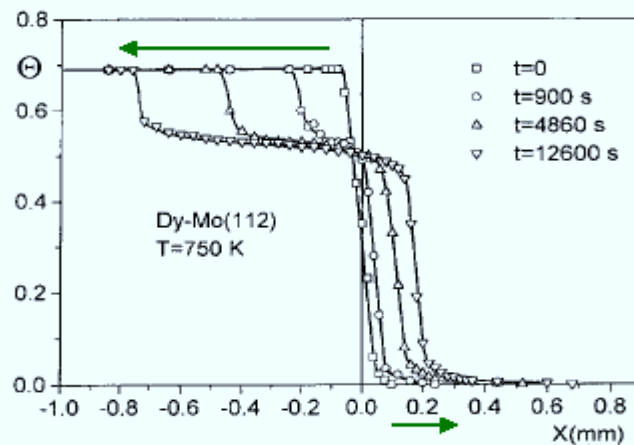


- Electric fields from the STM tip influence surface diffusion!

Experimental Techniques

2) Profile evolution method:

- Smearing of a sharp initial concentration profile is monitored
 - Initial profile deposited using a mask
 - AES, SIMS, SEM or local work-function...
 - $D(\Theta)$ can be evaluated
- Example: Dy on Mo(112) (Loburets et al., SS 1998)

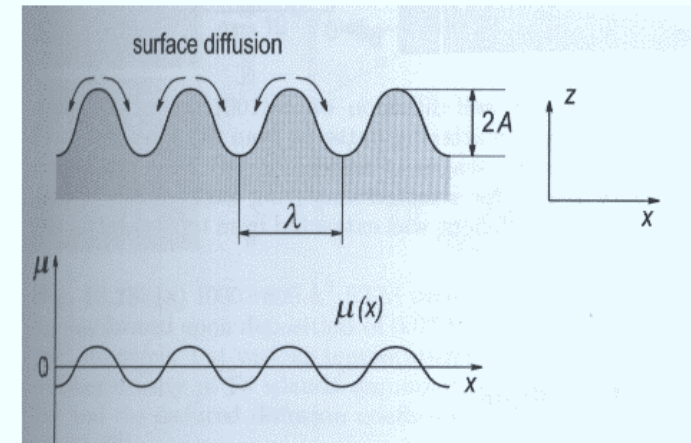


Experimental Techniques

3) “Capillarity” techniques:

- A surface is perturbed from its lowest energy configuration...
... and allowed to relax via diffusion
- Relaxation rate \rightarrow Coefficient of diffusion
- For a sinusoidal profile (Mullins, JAP 1999):

$$A(t) = A_0 \exp\left[-\frac{\gamma D n_0 V^2}{k_B T} \left(\frac{2\pi}{\lambda}\right)^4 t\right]$$

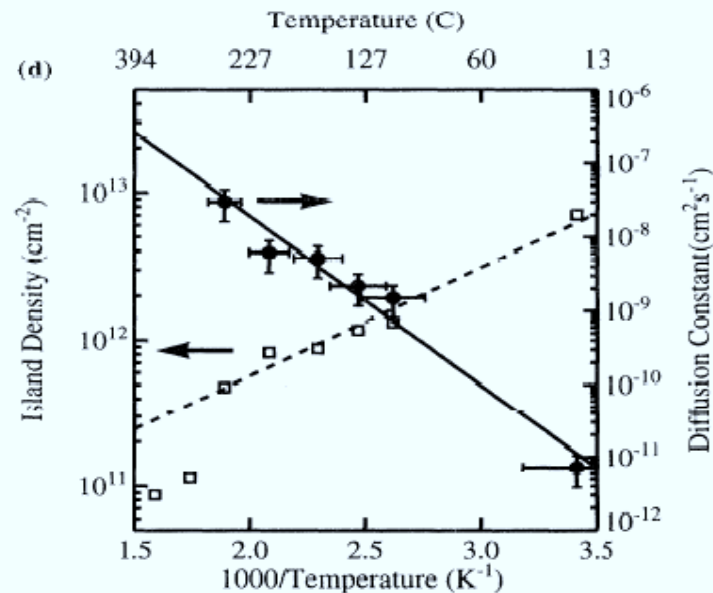
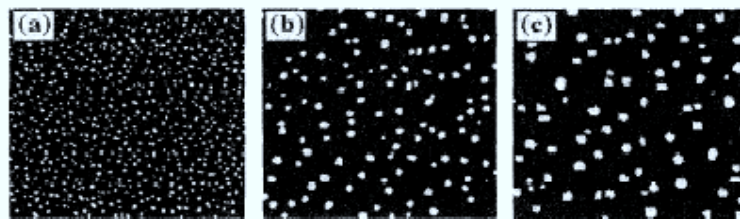


γ = surface tension; V = atomic volume; n_0 = surface density

Experimental Techniques

4) Island growth techniques:

- Number density of islands after submonolayer deposition is monitored
- Example: Fe on Fe(100) (Stroscio et al., PRL 1993)



$$N \propto \left(\frac{R\Theta}{\nu} \right)^{1/3}$$

deposition rate

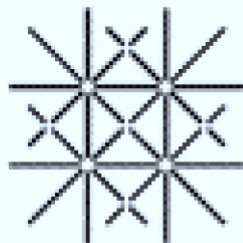
hopping rate

Further Reading

- K. Oura et al., Surface Science, Springer 2003, chapter 13
- A.G. Naumovets & Yu.S. Vedula, Surf. Sci. Rep. 4 (1985) 365
- R. Gomer, Rep. Prog. Phys. 53 (1990) 917
- G.L. Kellogg, Surf. Sci. Rep. 21 (1994) 1

Surface Physics 2010

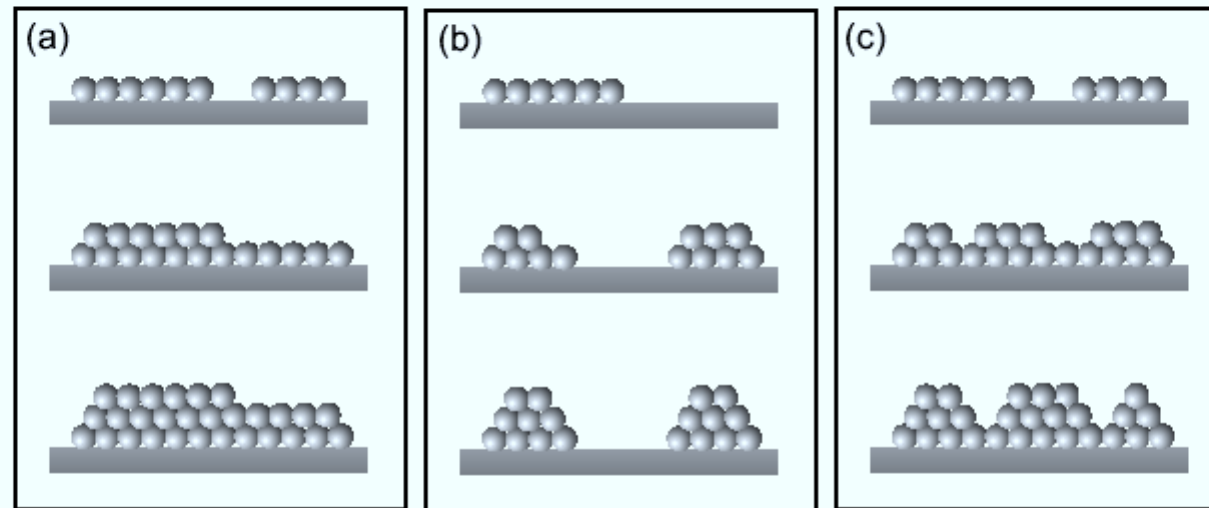
Growth of Thin Films



UNI
BASEL

Lecturer: Dr. Enrico Gnecco
NCCR Nanoscale Science

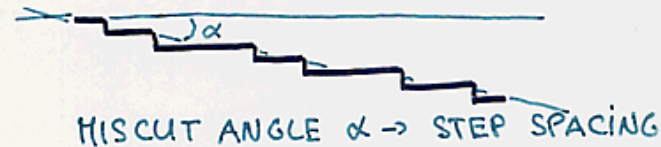
Growth Modes



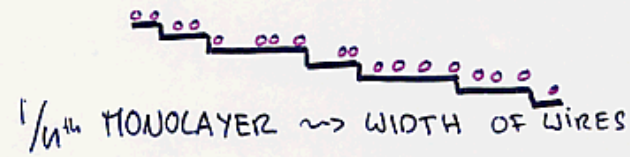
- (a) **Layer-by-layer** or **Frank-van der Merve** mode \rightarrow 2D islands
- (b) **Island** or **Vollmer-Weber** mode \rightarrow 3D islands
- (c) **Layer plus island** or **Stranski-Krastanov** mode \rightarrow 2D layer + 3D islands

"NANOWIRES" assly in parallel by Step Decoration & Controlling Growth.

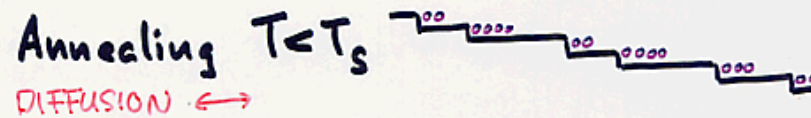
Sample
preparation.



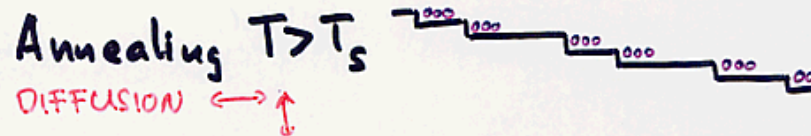
Adsorbate
deposition



Annealing $T < T_s$



Annealing $T > T_s$



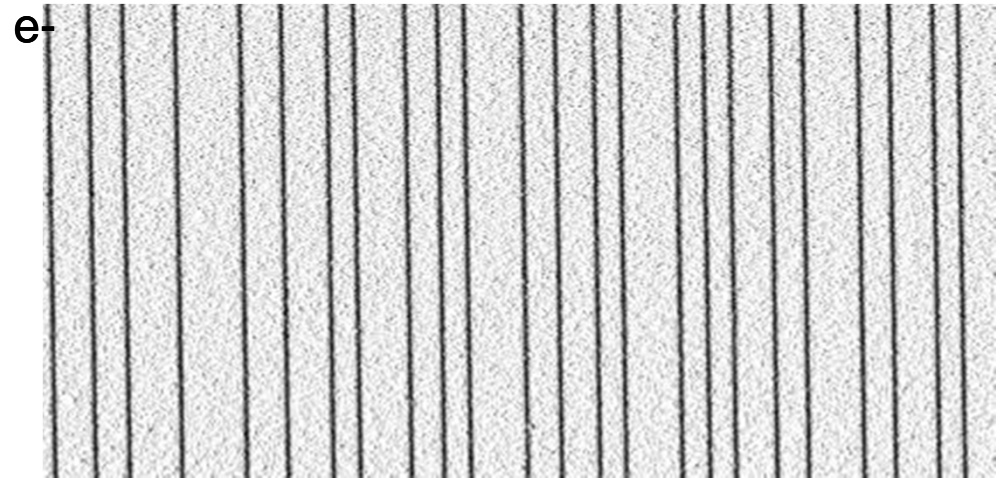
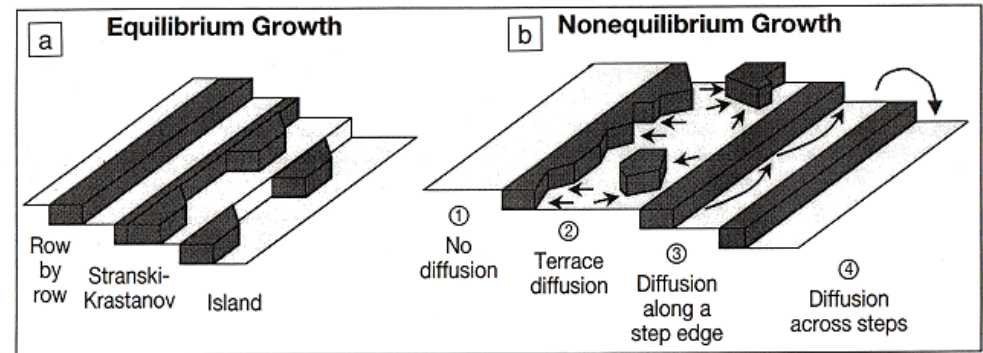
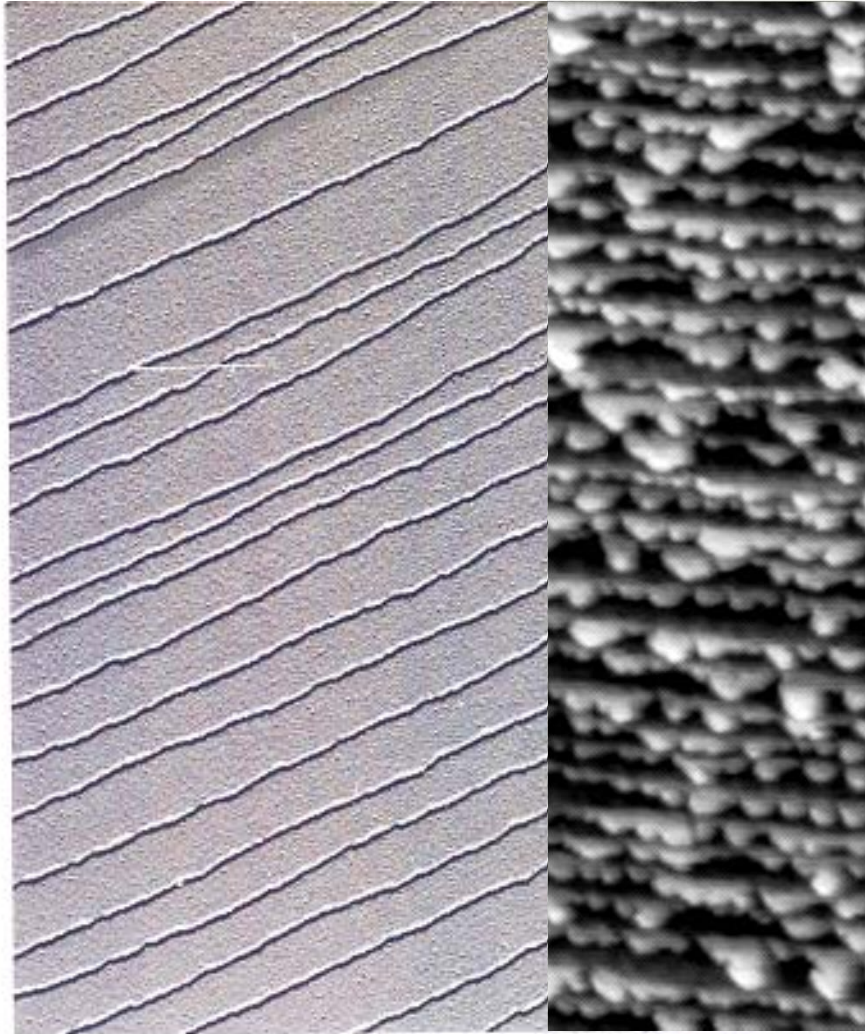
CONTROLLING GROWTH KINETICS:

Diffusion Anisotropy

\rightsquigarrow Preferential Growth in certain Direction

\rightsquigarrow Special Shapes of Grown Islands

'Physical' Self Assembly of e.g. Nanowires

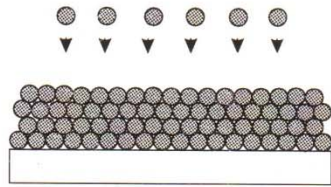


F. Himpsel, Th. Jung et al.
MRS Bulletin **24**, 20--24 (1999).

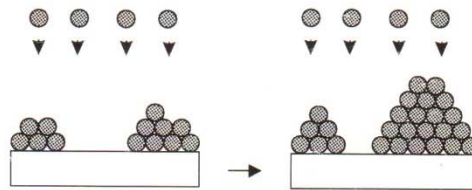
'Physical' Self Assembly of e.g. Nanowires jumping from 3D to 2D

Basic Growth Modes of Epitaxial Thin Films

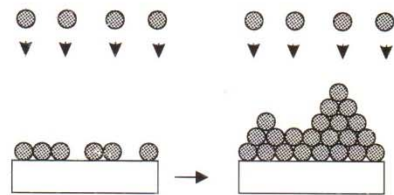
a) layer-by-layer growth



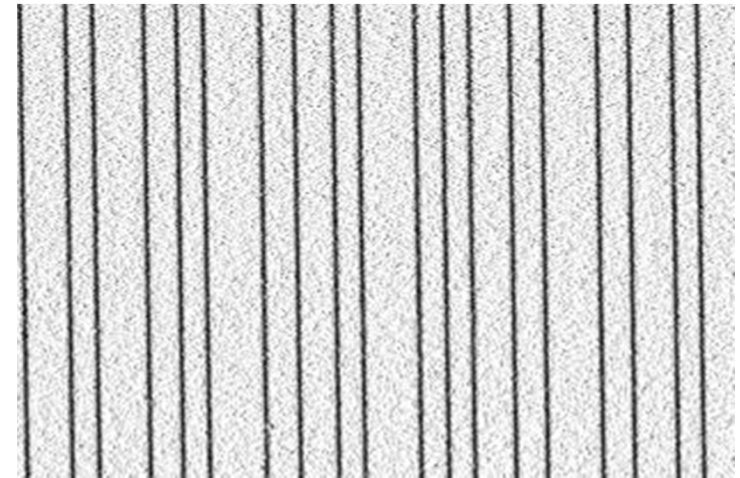
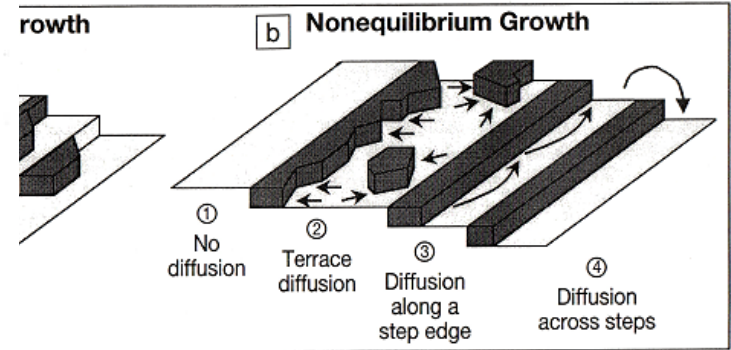
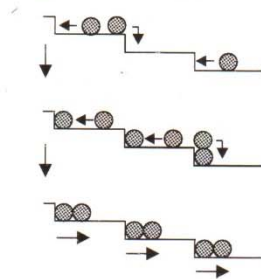
b) island growth



c) layer plus island growth



d) step flow growth ($l_T \ll l_D$)



Th. Jung et al.
n **24**, 20--24 (1999).

